

4 IDS 2/29/00 2874
J Royau

35.C13974

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
: Examiner: Not Yet Assigned
TADAHIRO OHMI, ET AL.)
: Group Art Unit: 2874
Application No.: 09/425,015)
: Filed: October 25, 1999)
: For: GAS SUPPLY PATH)
: STRUCTURE, GAS SUPPLY)
: METHOD, LASER OSCILLATING)
: APPARATUS, EXPOSURE)
: APPARATUS, AND DEVICE)
: PRODUCTION METHOD) February 17, 2000

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TECHNOLOGY CENTER 2800

Assistant Commissioner for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the document listed on the enclosed Form PTO-1449. A copy of the listed document is also enclosed.

The concise explanation of relevance for the non-English document, Japanese Patent Laid-Open Application No. 8-83945 may be found in the accompanying English abstracts describing an excimer laser oscillator.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


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